

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: **See Attached Schedule A**

Serial No.: **See Attached Schedule A**

Filed: **See Attached Schedule A**

For: **See Attached Schedule A**

Attorney Docket No: **See Attached
Schedule A**

REVOCATION AND POWER OF ATTORNEY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


S I R:

Aviza Technology, Inc., owner of the entire right, title and interest in, to and under the inventions listed in the attached Schedule A, hereby revokes all previous powers of attorney and appoints the registered attorneys at Morgan, Lewis & Bockius LLP associated with Customer No. **24341** as its attorneys to prosecute these matters, and to transact all business in the Patent and Trademark Office connected therewith, said appointment to be to the exclusion of the inventors and their attorney(s) in accordance with the provisions of 37 C.F.R. 3.71, provided that, if any one of these attorneys ceases being affiliated with the law firm of Morgan, Lewis & Bockius LLP as partner, counsel, or employee, then the appointment of that attorney and all powers derived therefrom shall terminate on the date such attorney ceases being so affiliated.

Please direct all future correspondence to the address associated with Customer No. **24341**, Morgan, Lewis & Bockius LLP and direct all telephone calls to Morgan, Lewis & Bockius LLP at (650) 843-4000.

Date: 08/03/2007

Assignee: **Aviza Technology, Inc.**

Signature: 

Typed Name: Nitin Shah

Position/Title: Vice President

Address: **440 Kings Village Road
Scotts Valley, California 95066**

SCHEDULE A

| Serial No./ Patent No. | Filing Date/ Issued Date | Title | First Named Inventor | Docket No. |
|---------------------------|-----------------------------|---|----------------------------|-----------------|
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| Serial No./ Patent No. | Filing Date/ Issued Date | Title | First Named Inventor | Docket No. |
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| 60/831,718 | 07/17/2006 | MICROFLUIDIC DEVICES | Gordon Robert Green | 67538-5025 PR |
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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|-----------------|--|---------------------|---|
| Application of: | Yoshihide Senzaki | Confirmation No.: | 2634 |
| Serial No. | 10/521,636 | Art Unit: | 2813 |
| Filed: | January 19, 2006 | Examiner: | Nguyen, Tuan H. |
| For: | In-Situ Formation of Metal Insulator Metal Capacitors | Attorney Docket No: | 067538-5167-US (previously A-71644/MSS (463035-877)) |

SUBMISSION UNDER 37 C.F.R. § 3.73(b)

Commissioner for Patents
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Alexandria, VA 22313-1450

Sir:

Aviza Technology, Inc., a corporation, states that it is the assignee of the entire right, title and interest in the patent application/patent identified above by virtue of an assignment from the inventor(s) of the patent application/patent identified above.

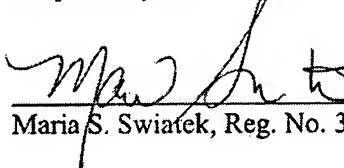
A chain of title from the inventor(s), of the patent application/patent identified above, to the current assignee as shown below:

1. From: Yoshihide Senzaki
To: Aviza Technology, Inc.

The document was recorded in the United States Patent and Trademark Office on January 6, 2006 at Reel 017572, Frame 0021.

The undersigned is authorized to act on behalf of the assignee.

Respectfully submitted,



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